

01-14-2004



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To the Honorable Commissioner of Patents and Trademarks: Please record the attached original documents or copy thereof.

## 1. Name of conveying party(ies):

MICROCOATING TECHNOLOGIES, INC.

Additional name(s) of conveying party(ies) attached? ☐ Yes ☒ No

## 3. Nature of conveyance:

☐ Assignment☐ Merger☒ Security Agreement☐ Change of Name☐ Other \_\_\_\_\_Execution Date: May 23, 2003

## 2. Name and address of receiving party(ies)

Name: SILICON VALLEY BANKInternal Address: Atlanta Financial CenterStreet Address: 3353 Peachtree Road, N.E.North Tower, Suite M-10City: Atlanta State: GA Zip: 30326Additional name(s) & addresses(es) attached? ☐ Yes ☒ No

## 4. Application number(s) or patent number(s):

If this document is being filed together with a new application, the execution date of the application is: \_\_\_\_\_:

A. Patent Application No.(s) 09291252, 09721605, 09733815, 09748714, 09781462, 09897157, 09889237, 09921437, 10030446, 10070958, 10111684, 10111696, 10150479, 60384991, 60389406, 60394494, 60396864, 60399067, 60399748, 60401288, 60401249, 60406070, 60406114, 60416781, 60425236, 60429529, 60430636, 10311785, 60438956, 10332866, 10341883, 10019082, 10362435, 10398641, 10421092, 09952881, and 10190292B. Patent No.(s) 5997956, 6132653, 6193911, 6207522, 6208234, 6212078, 6214473, 6270835, 6276347, 6368665, 6372364, 6390076, 6396387, 6403245, 6416870, 6433993, 4940328, 5623561, 5652021, 5858465, 5863604, 6013318, 6034015, 6545759, 6210592, 6329899, and 6500350Additional numbers attached? ☐ Yes ☒ No

## 5. Name and address of party to whom correspondence concerning document should be mailed:

Name: Ryan A. Schneider  
Troutman Sanders LLP

Internal Address: \_\_\_\_\_

Street Address: Bank of America Plaza, 600 Peachtree Street, NE, Suite 5200City: Atlanta State: GA Zip: 30308-22166. Total number of applications and patents involved: 647. Total fee (37 CFR 3.41).....\$2,560.00☒ Enclosed☒ Authorized to charge deficiency in fees to deposit account8. Deposit account number: 20-1507**RESUBMISSION OF RECORDATION SHEET, DOCUMENT ID NO. 102480899****DO NOT USE THIS SPACE**

## 9. Signature.

Ryan A. Schneider

Name of Person Signing

Docket Ref.: MICROCOATING

  
Signature6 January 2004

Date

Total number of pages including cover sheet, attachments, and documents: 43

Mail documents to be recorded with required cover sheet information to:

Commissioner of Patents & Trademarks, P.O. Box 1450, Mail Stop Assignment Recordation Services  
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6-19-03

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102480899

FORM PTO-1595  
(Rev. 10/02)  
OMB No. 0651-0027 (exp. 6/30/2005)

RECORDATION  
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To the Honorable Commissioner of Patents and Trademarks: Please record the attached original documents or copy thereof.

1. Name of conveying party(ies):  
  
MICROCOATING TECHNOLOGIES, INC.  
Additional name(s) of conveying party(ies) attached? ☐ Yes ☒ No

2. Name and address of receiving party(ies)  
Name: SILICON VALLEY BANK  
Internal Address: ✓  
Street Address: \_\_\_\_\_  
City: \_\_\_\_\_ State: \_\_\_\_\_ Zip: \_\_\_\_\_  
Additional name(s) & addresses(es) attached? ☐ Yes ☒ No

3. Nature of conveyance:  
  
☐ Assignment ☐ Merger  
☒ Security Agreement ☐ Change of Name  
☐ Other \_\_\_\_\_  
Execution Date: May 23, 2003

4. Application number(s) or patent number(s):  
If this document is being filed together with a new application, the execution date of the application is: \_\_\_\_\_  
A. Patent Application No.(s) 09291252, 09721605, 09733815, 09748714, 09781462, 09897157, 09889237, 09921437, 10030446, 10070958, 10111684, 10111696, 10150479, 60384991, 60389406, 60394494, 60396864, 60399067, 60399748, 60401288, 60401249, 60406070, 60406114, 60416781, 60425236, 60429529, 60430636, 10311785, 60438956, 10332866, 10341883, 10019082, 10362435, 10398641, 10421092, 09952881, and 10190292  
B. Patent No.(s) 5997956, 6132653, 6193911, 6207522, 6208234, 6212078, 6214473, 6270835, 6276347, 6368665, 6372364, 6390076, 6396387, 6403245, 6416870, 6433993, 4940328, 5623561, 5652021, 5858465, 5863604, 6013318, 6034015, 6545759, 6210592, 6329899, and 6500350  
Additional numbers attached? ☐ Yes ☒ No

5. Name and address of party to whom correspondence concerning document should be mailed:  
Name: Ryan A. Schneider  
Troutman Sanders LLP  
Internal Address: \_\_\_\_\_  
Street Address: Bank of America Plaza, 600 Peachtree Street, NE, Suite 5200  
City: Atlanta State: GA Zip: 30308-2216

6. Total number of applications and patents involved: 64  
7. Total fee (37 CFR 3.41).....\$2,560.00  
☒ Enclosed  
☒ Authorized to charge deficiency in fees to deposit account  
8. Deposit account number: 20-1507

06/23/2003 DIAZ1 00000139 09291252  
01 FC:3021 2560.00 OP

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9. Signature.  
Ryan A. Schneider  
Name of Person Signing

[Signature]  
Signature

June 19, 2003  
Date

Total number of pages including cover sheet, attachments, and documents: 43

Mail documents to be recorded with required cover sheet information to:  
Commissioner of Patents & Trademarks, P.O. Box 1450, Mail Stop Assignment Recordation Services  
Alexandria, VA 22313-1450

# INTELLECTUAL PROPERTY SECURITY AGREEMENT

This Intellectual Property Security Agreement is entered into as of May 23, 2003 by and between SILICON VALLEY BANK ("Bank") and MICROCOATING TECHNOLOGIES, INC. ("Grantor").

## RECITALS

A. Bank has agreed to make certain advances of money and to extend certain financial accommodation to Grantor (the "Loans") in the amounts and manner set forth in that certain Loan and Security Agreement by and between Bank and Grantor dated November 27, 2002 (as the same may be amended, modified or supplemented from time to time, the "Loan Agreement"; capitalized terms used herein and not otherwise defined shall have the meanings ascribed to such terms in the Loan Agreement). Bank is willing to make the Loans to Grantor, but only upon the condition, among others, that Grantor shall grant to Bank a security interest in certain Copyrights, Trademarks, Patents, and Mask Works to secure the obligations of Grantor under the Loan Agreement.

B. Pursuant to the terms of the Loan Agreement, Grantor has granted to Bank a security interest in all of Grantor's right, title and interest, whether presently existing or hereafter acquired, in, to and under all of the Collateral.

NOW, THEREFORE, for good and valuable consideration, receipt of which is hereby acknowledged, and intending to be legally bound, as collateral security for the prompt and complete payment when due of its obligations under the Loan Agreement, Grantor hereby represents, warrants, covenants and agrees as follows:

## AGREEMENT

To secure its obligations under the Loan Agreement, Grantor grants and pledges to Bank a security interest in all of Grantor's right, title and interest in, to and under its Intellectual Property Collateral (including without limitation those Copyrights, Patents, Patent License Agreements, Trademarks, and Mask Works listed on **Exhibits A, B1, B2, B3, B4, B5, B6, C and D** attached hereto), and including without limitation all proceeds thereof (such as, by way of example but not by way of limitation, license royalties and proceeds of infringement suits), the right to sue for past, present and future infringements, all rights corresponding thereto throughout the world and all re-issues, divisions continuations, renewals, extensions and continuations-in-part thereof.

This security interest is granted in conjunction with the security interest granted to Bank under the Loan Agreement. The rights and remedies of Bank with respect to the security interest granted hereby are in addition to those set forth in the Loan Agreement and the other Loan Documents, and those which are now or hereafter available to Bank as a matter of law or equity.

Each right, power and remedy of Bank provided for herein or in the Loan Agreement or any of the Loan Documents, or now or hereafter existing at law or in equity shall be cumulative and concurrent and shall be in addition to every right, power or remedy provided for herein and the exercise by Bank of any one or more of the rights, powers or remedies provided for in this Intellectual Property Security Agreement, the Loan Agreement or any of the other Loan Documents, or now or hereafter existing at law or in equity, shall not preclude the simultaneous or later exercise by any person, including Bank, of any or all other rights, powers or remedies. Grantor agrees that Bank shall be authorized to file financing statements, with all appropriate jurisdictions, without notice to Grantor, as Bank deems appropriate, in order to perfect or protect Bank's interest in the Intellectual Property Collateral.

IN WITNESS WHEREOF, the parties have caused this Intellectual Property Security Agreement to be duly executed by its officers as of the first date written above.

GRANTOR:

MICROCOATING TECHNOLOGIES,  
INC.

By: da smith  
Name: DAVID A. SMITH  
Title: CFO

BANK:

SILICON VALLEY BANK

By: \_\_\_\_\_  
Name: \_\_\_\_\_  
Title: \_\_\_\_\_

Each right, power and remedy of Bank provided for herein or in the Loan Agreement or any of the Loan Documents, or now or hereafter existing at law or in equity shall be cumulative and concurrent and shall be in addition to every right, power or remedy provided for herein and the exercise by Bank of any one or more of the rights, powers or remedies provided for in this Intellectual Property Security Agreement, the Loan Agreement or any of the other Loan Documents, or now or hereafter existing at law or in equity, shall not preclude the simultaneous or later exercise by any person, including Bank, of any or all other rights, powers or remedies. Grantor agrees that Bank shall be authorized to file financing statements, with all appropriate jurisdictions, without notice to Grantor, as Bank deems appropriate, in order to perfect or protect Bank's interest in the Intellectual Property Collateral.

IN WITNESS WHEREOF, the parties have caused this Intellectual Property Security Agreement to be duly executed by its officers as of the first date written above.

GRANTOR:

MICROCOATING TECHNOLOGIES,  
INC.

By: \_\_\_\_\_  
Name: \_\_\_\_\_  
Title: \_\_\_\_\_

BANK:

SILICON VALLEY BANK

By: Laura M. Scott  
Name: Laura M. Scott  
Title: Senior Vice President

**EXHIBIT A**  
**COPYRIGHTS**

None

**EXHIBIT B1**

**ISSUED PATENTS OWNED BY MCT**

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Patent #:** 5,997,956 **Country:** U.S.

**Issue date:** 12/7/1999 **Status:** Issued, Expires 8/2/16

**Government Contract (see below)** **Licensee(s):** Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Patent #:** 6,132,653 **Country:** U.S.

**Issue date:** 10/17/2000 **Status:** Issued, Expires 8/2/16

**Government Contract (see below)** **Licensee(s):** Shipley, Ballard

**Title:** PRECURSOR SOLUTION COMPOSITIONS FOR ELECTRONIC DEVICES USING CCVD

**Patent #:** 6,193,911 **Country:** U.S.

**Issue date:** 2/27/2001 **Status:** Issued, Expires 4/29/2018

**Government Contract (see below)** **Licensee(s):** Shipley

**Title:** FORMATION OF THIN FILM CAPACITORS

**Patent #:** 6,207,522 **Country:** U.S.

**Issue date:** 3/27/2001 **Status:** Issued, Expires 11/23/2018

**Government Contract (see below)** **Licensee(s):** Shipley

**Title:** RESISTORS FOR ELECTRONIC PACKAGING

**Patent #:** 6,208,234 **Country:** U.S.

**Issue date:** 3/27/2001 **Status:** Issued, Expires 4/29/2018

**Government Contract (see below)** **Licensee(s):** Shipley

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

**Patent #:** 6,212,078 **Country:** U.S.

**Issue date:** 4/3/2001 **Status:** Issued, Expires 10/27/2019

**Government Contract (see below)** **Licensee(s):** Shipley

**Title:** CORROSION-RESISTANT MULTILAYER COATING

**Patent #:** 6,214,473 **Country:** U.S.

<b>Government Contract (see below)</b>	<b>Licensee(s):</b>	<b>Issue date:</b> 4/10/2001	<b>Status:</b> Issued, Expires 5/13/2018
<b>Title:</b> FORMATION OF THIN FILM CAPACITORS		<b>Patent #:</b> 6,270,835	<b>Country:</b> U.S.
<b>Government Contract (see below)</b>	<b>Licensee(s):</b> Shipley	<b>Issue date:</b> 8/7/2001	<b>Status:</b> Issued, Expires 11/23/18
<b>Title:</b> SYSTEMS AND METHODS FOR DELIVERING ATOMIZED FLUIDS		<b>Patent #:</b> 6,276,347	<b>Country:</b> U.S.
<b>Government Contract (see below)</b>	<b>Licensee(s):</b>	<b>Issue date:</b> 8/21/2001	<b>Status:</b> Issued, Expires 9/25/18
<b>Title:</b> FORMATION OF THIN FILM CAPACITORS		<b>Patent #:</b> 144618	<b>Country:</b> Taiwan
<b>Government Contract (see below)</b>	<b>Licensee(s):</b> Shipley	<b>Issue date:</b> 10/21/2001	<b>Status:</b> Issued, Expires 11/23/18
<b>Title:</b> APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION		<b>Patent #:</b> 0322784	<b>Country:</b> South Korea
<b>Government Contract (see below)</b>	<b>Licensee(s):</b> Shipley	<b>Issue date:</b> 1/18/2002	<b>Status:</b> Issued, Expires 4/29/18
<b>Title:</b> APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION		<b>Patent #:</b> 6,368,665	<b>Country:</b> U.S.
<b>Government Contract (see below)</b>	<b>Licensee(s):</b> Shipley	<b>Issue date:</b> 4/9/2002	<b>Status:</b> Issued, Expires 4/29/18
<b>Title:</b> NANOSTRUCTURE COATINGS		<b>Patent #:</b> 6,372,364	<b>Country:</b> U.S.
<b>Government Contract (see below)</b>	<b>Licensee(s):</b>	<b>Issue date:</b> 4/16/2002	<b>Status:</b> Issued, Expires 8/18/19
<b>Title:</b> SYSTEMS AND METHODS FOR DELIVERING ATOMIZED FLUIDS		<b>Patent #:</b> 6,390,076	<b>Country:</b> U.S.

**Government Contract (see below)**      **Licensee(s):**      **Issue date:** 5/21/2002      **Status:** Issued, Expires 9/25/18

**Title:** RESISTORS FOR ELECTRONIC PACKAGING      **Patent #:** 6,396,387      **Country:** U.S.

**Government Contract (see below)**      **Licensee(s):** Shipley      **Issue date:** 5/28/2002      **Status:** Issued, Expires 4/29/18

**Title:** MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES      **Patent #:** 6,403,245      **Country:** U.S.

**Government Contract (see below)**      **Licensee(s):** Ballard      **Issue date:** 6/11/2002      **Status:** Issued, Expires 5/21/19

**Title:** CORROSION RESISTANT MULTILAYER COATINGS      **Patent #:** 6,416,870      **Country:** U.S.

**Government Contract (see below)**      **Licensee(s):**      **Issue date:** 7/9/2002      **Status:** Issued, Expires 5/13/18

**Title:** CORROSION-RESISTANT MULTILAYER COATING      **Patent #:** 745998      **Country:** Australia

**Government Contract (see below)**      **Licensee(s):**      **Issue date:** 7/25/2002      **Status:** Issued, Expires 5/13/18

**Title:** FORMATION OF THIN FILM CAPACITORS      **Patent #:** 6,433,993      **Country:** U.S.

**Government Contract (see below)**      **Licensee(s):** Shipley      **Issue date:** 8/13/2002      **Status:** Issued, Expires 11/23/18

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION      **Patent #:** 956865      **Country:** Israel

**Government Contract (see below)**      **Licensee(s):** Shipley      **Issue date:** 10/1/2002      **Status:** Issued

**EXHIBIT B2**  
ISSUED PATENTS OWNED BY GEORGIA TECH RESEARCH  
CORP. AND EXCLUSIVELY LICENSED BY MCT

<b>Title:</b>	OPTICAL SENSING APPARATUS AND METHOD	<b>Patent #:</b>	4,940,328	<b>Country:</b>	U.S.
<b>Government Contract</b>	<b>Licensee(s)</b>	<b>Issue date:</b>	7/10/1990	<b>Status:</b>	Issued, Expires 11/4/08

<b>Title:</b>	OPTICAL SENSING APPARATUS AND METHOD	<b>Patent #:</b>	2,002,353	<b>Country:</b>	Canada
<b>Government Contract</b>	<b>Licensee(s)</b>	<b>Issue date:</b>	1/17/1995	<b>Status:</b>	Issued, Expires 11/4/08

<b>Title:</b>	OPTICAL SENSING APPARATUS AND METHOD	<b>Patent #:</b>	2041773	<b>Country:</b>	Japan
<b>Government Contract</b>	<b>Licensee(s)</b>	<b>Issue date:</b>	4/9/1996	<b>Status:</b>	Issued, Expires 11/4/08

<b>Title:</b>	OPTICAL SENSING APPARATUS AND METHOD	<b>Patent #:</b>	0 441 898	<b>Country:</b>	Europe
<b>Government Contract</b>	<b>Licensee(s)</b>	<b>Issue date:</b>	1/8/1997	<b>Status:</b>	Issued, Expires 11/4/08

<b>Title:</b>	INTEGRATED OPTIC INTERFEROMETRIC SENSOR	<b>Patent #:</b>	5,623,561	<b>Country:</b>	U.S.
<b>Government Contract</b>	<b>Licensee(s)</b>	<b>Issue date:</b>	4/22/1997	<b>Status:</b>	Issued, Expires 9/29/15

<b>Title:</b>	METHODS AND APPARATUS FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS	<b>Patent #:</b>	5,652,021	<b>Country:</b>	U.S.
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**Government Contract**      **Licensee(s)**      Shipley, Ballard      **Issue date:**      7/29/1997      **Status:**      Issued, Expires 7/29/2014

**Title:** COMBUSTION CHEMICAL VAPOR DEPOSITION OF PHOSPHATE FILMS AND COATINGS

**Patent #:**      5,858,465      **Country:**      U.S.  
**Issue date:**      1/12/1999      **Status:**      Issued, Expires 3/24/2013

**Government Contract**      **Licensee(s)**      Shipley

**Title:** METHOD FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS

**Patent #:**      5,863,604      **Country:**      U.S.  
**Issue date:**      1/26/1999      **Status:**      Issued, Expires 3/24/2013

**Government Contract**      **Licensee(s)**      Shipley, Ballard

**Title:** METHOD FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS

**Patent #:**      6,013,318      **Country:**      U.S.  
**Issue date:**      1/11/2000      **Status:**      Issued, Expires 3/24/2013

**Government Contract**      **Licensee(s)**      Shipley, Ballard

**Title:** CERAMIC COMPOSITIONS FOR MICROWAVE COMMUNICATIONS

**Patent #:**      6,034,015      **Country:**      U.S.  
**Issue date:**      3/7/2000      **Status:**      Issued, Expires 5/14/2018

**Government Contract**      **Licensee(s)**

**Title:** METHODS AND APPARATUS FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS

**Patent #:**      2,158,568      **Country:**      Canada  
**Issue date:**      12/4/2001      **Status:**      Issued, Expires 3/24/13

**Government Contract**      **Licensee(s)**      Shipley, Ballard

**Title:** METHODS AND APPARATUS FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS

**Patent #:**      323216      **Country:**      South Korea  
**Issue date:**      1/22/2002      **Status:**      Issued, Expires 3/24/13

**Government Contract**      **Licensee(s)**      Shipley, Ballard

**Title:** INTEGRATED OPTIC INTERFEROMETRIC SENSOR

**Government Contract**      **Licensee(s)**

**Patent #:**      0 852 715      **Country:**      Europe

**Issue date:**      5/2/2002      **Status:**      Issued, Expires 9/29/15

**Title:** COMBUSTION CHEMICAL VAPOR DEPOSITION OF PHOSPHATE FILMS AND COATINGS

**Government Contract**      **Licensee(s)**      Shipley

**Patent #:**      745098      **Country:**      Australia

**Issue date:**      6/27/2002      **Status:**      Issued, Expires 3/24/13

**Title:** TRANSVERSE INTEGRATED OPTIC INTERFEROMETER

**Government Contract**      **Licensee(s)**

**Patent #:**      6,545,759      **Country:**      U.S.

**Issue date:**      4/8/2003      **Status:**      Issued, expires 11/30/19

Exhibit B3

PATENT APPLICATIONS OWNED BY MCT

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Application #:** JP 9-508559 **Country:** Japan

**Date filed:** 8/2/1996 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Application #:** 96 928 045 2 **Country:** Europe

**Date filed:** 8/2/1996 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Application #:** 1998-700815 **Country:** South Korea

**Date filed:** 8/2/1996 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Application #:** 980986 **Country:** Mexico

**Date filed:** 8/2/1996 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Application #:** P196100699 **Country:** Brazil

**Date filed:** 8/2/1996 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:** 88104056 **Country:** Taiwan

**Date filed:** 3/16/1999 **Status:** Allowed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:**      455/DEL/99      **Country:**      India

**Date filed:**      3/22/1999      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:**      99016552      **Country:**      Singapore

**Date filed:**      4/7/1999      **Status:**      Allowed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** PRECURSOR SOLUTION COMPOSITIONS FOR ELECTRONIC DEVICES USING CCVD

**Application #:**      09/291,252      **Country:**      U.S.

**Date filed:**      4/13/1999      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:**      993646      **Country:**      Mexico

**Date filed:**      4/20/1999      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:**      2,269,862      **Country:**      Canada

**Date filed:**      4/26/1999      **Status:**      Allowed 1/8/03

**Government Contract**      **Licensee(s):**      Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:**      99012871      **Country:**      Brazil

**Date filed:**      4/27/1999      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:** 00104196.4 **Country:** Hong Kong

**Date filed:** 4/29/1999 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:** 991053850 **Country:** China

**Date filed:** 4/29/1999 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:** 99303373.7 **Country:** Europe

**Date filed:** 4/29/1999 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley

**Title:** APPARATUS AND PROCESS FOR CONTROLLED ATMOSPHERE CHEMICAL VAPOR DEPOSITION

**Application #:** 111124905 **Country:** Japan

**Date filed:** 4/30/1999 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley

**Title:** CORROSION-RESISTANT MULTILAYER COATING

**Application #:** 2,296,505 **Country:** Canada

**Date filed:** 5/13/1999 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** SYSTEMS AND METHODS FOR DELIVERING ATOMIZED FLUIDS

**Application #:** EP 99952953.0 **Country:** Europe

**Date filed:** 9/23/1999 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** FORMATION OF THIN FILM CAPACITORS

**Application #:** 2289239 **Country:** Canada

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/10/1999      **Status:**      Filed

**Title:**      FORMATION OF THIN FILM CAPACITORS

**Application #:**      132834      **Country:**      Israel

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/10/1999      **Status:**      Filed

**Title:**      FORMATION OF THIN FILM CAPACITORS

**Application #:**      00107629.4      **Country:**      Hong Kong

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/17/1999      **Status:**      Filed

**Title:**      FORMATION OF THIN FILM CAPACITORS

**Application #:**      10-1999-0051164      **Country:**      South Korea

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/17/1999      **Status:**      Filed

**Title:**      FORMATION OF THIN FILM CAPACITORS

**Application #:**      99309146.1      **Country:**      Europe

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/17/1999      **Status:**      Filed

**Title:**      FORMATION OF THIN FILM CAPACITORS

**Application #:**      991244885      **Country:**      China

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/23/1999      **Status:**      Filed

**Title:**      FORMATION OF THIN FILM CAPACITORS

**Application #:**      99333500      **Country:**      Japan

**Government Contract**      **Licensee(s):**      Shipley

**Date filed:**      11/24/1999      **Status:**      Filed

**Title:** CORROSION-RESISTANT MULTILAYER COATING

<b>Government Contract</b>	<b>Licensee(s):</b>	<b>Application #:</b> 99 923 038.6	<b>Country:</b> Europe
		<b>Date filed:</b> 1/13/2000	<b>Status:</b> Filed

**Title:** CORROSION-RESISTANT MULTILAYER COATING

<b>Government Contract</b>	<b>Licensee(s):</b>	<b>Application #:</b> 2000-548522	<b>Country:</b> Japan
		<b>Date filed:</b> 1/13/2000	<b>Status:</b> Filed

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

<b>Government Contract</b>	<b>Licensee(s):</b> Shipley	<b>Application #:</b> 00309340.8	<b>Country:</b> Europe
		<b>Date filed:</b> 10/24/2000	<b>Status:</b> Filed

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

<b>Government Contract</b>	<b>Licensee(s):</b> Shipley	<b>Application #:</b> 10-2000-0063292	<b>Country:</b> South Korea
		<b>Date filed:</b> 10/27/2000	<b>Status:</b> Filed

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

<b>Government Contract</b>	<b>Licensee(s):</b> Shipley	<b>Application #:</b> 329569/2000	<b>Country:</b> Japan
		<b>Date filed:</b> 10/27/2000	<b>Status:</b> Filed

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

<b>Government Contract</b>	<b>Licensee(s):</b> Shipley	<b>Application #:</b> 89122645	<b>Country:</b> Taiwan
		<b>Date filed:</b> 10/27/2000	<b>Status:</b> Filed

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

<b>Government Contract</b>	<b>Licensee(s):</b> Shipley	<b>Application #:</b> 00137023.5	<b>Country:</b> China
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**Government Contract**      **Licensee(s):**      Shipley      **Date filed:**      10/27/2000      **Status:**      Filed

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

**Application #:**      200006502-9      **Country:**      Singapore  
**Date filed:**      10/27/2000      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** RESISTORS FOR ELECTRONIC PACKAGING

**Application #:**      09/721,605--2748      **Country:**      U.S.  
**Date filed:**      11/22/2000      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** FORMATION OF THIN FILM CAPACTORS

**Application #:**      09/733,815      **Country:**      U.S.  
**Date filed:**      12/9/2000      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING POWDERS AND COATINGS, AND COATINGS MADE USING THESE METHODS

**Application #:**      09/748,714--4539      **Country:**      U.S.  
**Date filed:**      12/21/2000      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION METHOD AND COATINGS PRODUCED THEREFROM

**Application #:**      200203931-1      **Country:**      Singapore  
**Date filed:**      12/21/2000      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING POWDERS AND COATINGS, AND COATINGS MADE USING THESE METHODS

**Application #:**      00 990 367.5      **Country:**      Europe  
**Date filed:**      12/21/2000      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** NANOLAMINATED THIN FILM CIRCUITRY MATERIALS

**Application #:**      09/781,462      **Country:**      U.S.

**Date filed:**      2/12/2001      **Status:**      Allowed

**Government Contract**      **Licensee(s):**      Shipley

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY WITH NEAR SUPERCRITICAL FLUID SOLUTIONS

**Application #:**      09/897,157 - 2888      **Country:**      U.S.

**Date filed:**      7/3/2001      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** EPITAXIAL THIN FILMS

**Application #:**      2,359,710      **Country:**      Canada

**Date filed:**      7/9/2001      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** EPITAXIAL THIN FILMS

**Application #:**      09/889,237 - 8868      **Country:**      U.S.

**Date filed:**      7/10/2001      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** EPITAXIAL THIN FILMS

**Application #:**      008045860      **Country:**      China

**Date filed:**      7/11/2001      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** EPITAXIAL THIN FILMS

**Application #:**      2000-594127      **Country:**      Japan

**Date filed:**      7/12/2001      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** EPITAXIAL THIN FILMS

**Application #:** IN/PCT/2001/0062      **Country:** India

**Date filed:** 7/12/2001      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** REDUCED GRAIN BOUNDARY CRYSTALLINE THIN FILMS

**Application #:** 90117374      **Country:** Taiwan

**Date filed:** 7/16/2001      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL MATERIALS

**Application #:** 90119036      **Country:** Taiwan

**Date filed:** 8/3/2001      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION USING THERMAL SPRAY  
WITH NEAR SUPERCRITICAL AND SUPERCRITICAL FLUID SOLUTIONS

**Application #:** 09/921,437-8003      **Country:** U.S.

**Date filed:** 8/3/2001      **Status:** Filed

**Government Contract**      **Licensee(s):** Shipley, Ballard

**Title:** EPITAXIAL THIN FILMS

**Application #:** 2001122592      **Country:** Russia

**Date filed:** 8/10/2001      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** EPITAXIAL THIN FILMS

**Application #:** 41656/00      **Country:** Australia

**Date filed:** 8/12/2001      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** EPITAXIAL THIN FILMS

**Application #:** 00 921 311.7      **Country:** Europe

**Government Contract**      **Licensee(s):**

**Date filed:**                      8/12/2001      **Status:**      Filed

**Title:**      ELECTRONIC AND OPTICAL DEVICES AND METHODS OF FORMING THESE DEVICES

**Application #:**                      90121036                      **Country:**                      Taiwan

**Date filed:**                      8/29/2001                      **Status:**                      Filed

**Title:**      OPTICAL WAVEGUIDES AND INTEGRATED OPTICAL SUBSYSTEMS ON-A-CHIP

**Government Contract**      **Licensee(s):**

**Application #:**                      PCT/US01/30282                      **Country:**                      International

**Date filed:**                      9/27/2001                      **Status:**                      Filed

**Title:**      OPTICAL WAVEGUIDES AND INTEGRATED OPTICAL SUBSYSTEMS ON-A-CHIP

**Government Contract**      **Licensee(s):**

**Application #:**                      90124425                      **Country:**                      Taiwan

**Date filed:**                      10/3/2001                      **Status:**                      Allowed

**Title:**      FUEL CELL HAVING IMPROVED CATALYTIC LAYER

**Government Contract**      **Licensee(s):**                      Ballard

**Application #:**                      PCT/US01/48581                      **Country:**                      International

**Date filed:**                      10/26/2001                      **Status:**                      Filed

**Title:**      MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES

**Government Contract**      **Licensee(s):**                      Ballard

**Application #:**                      2,371,428                      **Country:**                      Canada

**Date filed:**                      11/19/2001                      **Status:**                      Filed

**Title:**      MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES

**Application #:**                      2000-620687                      **Country:**                      Japan

**Government Contract**      **Licensee(s):**    Ballard      **Date filed:**      11/21/2001    **Status:**    Filed

**Title:** MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES

**Government Contract**      **Licensee(s):**    Ballard      **Application #:**    PA/a/2001/011968    **Country:**    Mexico  
**Date filed:**      11/21/2001    **Status:**    Filed

**Title:** MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES

**Government Contract**      **Licensee(s):**    Ballard      **Application #:**           **Country:**    India  
**Date filed:**      11/21/2001    **Status:**    Filed

**Title:** MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES

**Government Contract**      **Licensee(s):**    Ballard      **Application #:**    00936152.8-2119-    **Country:**    Europe  
**Date filed:**      11/21/2001    **Status:**    Filed

**Title:** METHOD OF COATING CERAMICS USING CCVD

**Government Contract**      **Licensee(s):**           **Application #:**    00943355.8      **Country:**    Europe  
**Date filed:**      11/29/2001    **Status:**    Filed

**Title:** MATERIALS AND PROCESSES FOR PROVIDING FUEL CELLS AND ACTIVE MEMBRANES

**Government Contract**      **Licensee(s):**    Ballard      **Application #:**    51513/00      **Country:**    Australia  
**Date filed:**      12/21/2001    **Status:**    Filed

**Title:** CHEMICAL VAPOR DEPOSITION DEVICES AND METHODS

**Application #:**    PCT/US01/49559    **Country:**    International  
**Date filed:**      12/27/2001    **Status:**    Filed

**Government Contract**      **Licensee(s):**

**Title:** METHOD OF COATING CERAMICS USING CCVD

**Government Contract**      **Licensee(s):**

**Title:** NANOSTRUCTURE COATINGS

**Government Contract**      **Licensee(s):**

**Title:** NANOSTRUCTURE COATINGS

**Government Contract**      **Licensee(s):**

**Title:** NANOSTRUCTURE COATINGS

**Government Contract**      **Licensee(s):**

**Title:** NANOSTRUCTURE COATINGS

**Government Contract**      **Licensee(s):**

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Government Contract**      **Licensee(s):** Shipley , Ballard

**Application #:** 10/030,446      **Country:** U.S.

**Date filed:** 1/2/2002      **Status:** Filed

**Application #:** IN/PCT/2002,      **Country:** India

**Date filed:** 2/14/2002      **Status:** Filed

**Application #:** 200200884-5      **Country:** Singapore

**Date filed:** 2/15/2002      **Status:** Filed

**Application #:** P1001 3378-7      **Country:** Brazil

**Date filed:** 2/18/2002      **Status:** Filed

**Application #:** EP00955757.0      **Country:** Europe

**Date filed:** 2/18/2002      **Status:** Filed

**Application #:** 200201422-3      **Country:** Singapore

**Date filed:** 3/12/2002      **Status:** Filed

**PATENT**

**REEL: 014901 FRAME: 0285**

**Title:** LIQUID ATOMIZATION METHOD AND DEVICES

**Application #:** 10/070,958 - 4878 **Country:** U.S.

**Date filed:** 3/12/2002 **Status:** Allowed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:** PA/a/2002/002780 **Country:** Mexico

**Date filed:** 3/14/2002 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley Ballard

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:** 2001-524736 **Country:** Japan

**Date filed:** 3/20/2002 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:** PI 001 4185-2 **Country:** Brazil

**Date filed:** 3/21/2002 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:** 2,385,324 **Country:** Canada

**Date filed:** 3/22/2002 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:** 00968397.0 **Country:** Europe

**Date filed:** 3/22/2002 **Status:** Filed

**Government Contract** **Licensee(s):** Shipley, Ballard

**Title:** LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:** IN/PCT/2002, **Country:** India

**Government Contract**      **Licensee(s):**      Shipley , Ballard

**Title:**    LIQUID ATOMIZATION METHODS AND DEVICES

**Date filed:**                      3/22/2002      **Status:**      Filed

**Application #:**                148743                      **Country:**      Israel

**Date filed:**                      3/22/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley , Ballard

**Title:**    VARIABLE CAPACITORS, COMPOSITE MATERIALS

**Application #:**                PCT/US02/11133              **Country:**      International

**Date filed:**                      4/9/2002      **Status:**      Chapter II filed

**Government Contract**      **Licensee(s):**

**Title:**    METHOD OF DEPOSITING MATERIALS

**Application #:**                10/111,684 - 5880              **Country:**      U.S.

**Date filed:**                      4/17/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:**    PROCESSING LINE HAVING MEANS TO MONITOR CRYSTALLOGRAPHIC OREINTATION

**Application #:**                10/111,696 - 4564              **Country:**      U.S.

**Date filed:**                      4/17/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:**    LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:**                78322/00                      **Country:**      Australia

**Date filed:**                      4/18/2002      **Status:**      Filed, Exam Requested

**Government Contract**      **Licensee(s):**      Shipley , Ballard

**Title:**    LIQUID ATOMIZATION METHODS AND DEVICES

**Application #:**                2002110464                      **Country:**      Russia

**Date filed:**                      4/19/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley , Ballard

**Title:** CAPACITOR WITH IMPROVED ELECTRODE STRUCTURE

**Application #:** PCT/US02/14861      **Country:** International  
**Date filed:** 5/9/2002      **Status:** Allowed

**Government Contract**      **Licensee(s):**

**Title:** VARIABLE DIRECTION RESISTIVE MATERIAL

**Application #:** 10/150,479      **Country:** U.S.  
**Date filed:** 5/17/2002      **Status:** Filed

**Government Contract**      **Licensee(s):** Shipley

**Title:** TRANSVERSE INTEGRATED OPTIC INTERFEROMETER

**Application #:** 2,393,076      **Country:** Canada  
**Date filed:** 5/29/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** TRANSVERSE INTEGRATED OPTIC INTERFEROMETER

**Application #:** 00 992 553.8      **Country:** Europe  
**Date filed:** 5/30/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** BARRIER COATING, METHOD OF FORMATION

**Application #:** 60/384,991 1966      **Country:** U.S. Provisional  
**Date filed:** 5/31/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING POWDERS AND COATINGS, AND COATINGS MADE USING THESE METHODS

**Application #:** 2,393,531      **Country:** Canada  
**Date filed:** 6/3/2002      **Status:** Filed

**Government Contract**      **Licensee(s):** Shipley, Ballard

**Title:** BARRIER COATINGS

**Application #:** 60/389,406 -4127      **Country:** U.S. Provisional  
**Date filed:** 6/17/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** METHOD FOR THERMAL MANAGEMENT OF INTERNAL COMBUSTION ENGINES

**Government Contract**      **Licensee(s):**

**Title:** CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING POWDERS AND COATINGS,  
AND COATINGS MADE USING THESE METHODS

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING POWDERS AND COATINGS,  
AND COATINGS MADE USING THESE METHODS

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** TELECOMMUNICATIONS CIRCUITRY

**Government Contract**      **Licensee(s):**

**Title:** MULTI-BAND TRANSCEIVER

**Government Contract**      **Licensee(s):**

**Title:** SELECTIVE AREA DEPOSITION OF CIRCUITRY LAYERS

**Government Contract**      **Licensee(s):**

**Application #:**      PCT/US02/19038      **Country:**      International  
**Date filed:**      6/17/2002      **Status:**      Filed, No Chapter II

**Application #:**      IN/PCT/2002/0073      **Country:**      India  
**Date filed:**      6/29/2002      **Status:**      Filed

**Application #:**      PI 0016782-7      **Country:**      Brazil  
**Date filed:**      6/29/2002      **Status:**      Filed

**Application #:**      60/394,494 - 6460      **Country:**      U.S. Provisional  
**Date filed:**      7/9/2002      **Status:**      Filed

**Application #:**      60/396,864 - 3385      **Country:**      U.S. Provisional  
**Date filed:**      7/18/2002      **Status:**      Filed

**Application #:**      60/399,067      **Country:**      U.S. Provisional  
**Date filed:**      7/26/2002      **Status:**      Filed

**Title:** CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING POWDERS AND COATINGS, AND COATINGS MADE USING THESE METHODS

**Application #:** 27402/01      **Country:** Australia  
**Date filed:** 7/29/2002      **Status:** Filed

**Government Contract**      **Licensee(s):** Shipley, Ballard

**Title:** INTEGRATED-OPTIC CROSS-CONNECT SWITCH

**Application #:** 60/399,748      **Country:** U.S. Provisional  
**Date filed:** 7/30/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** OPTICAL/RF HYBRID CIRCUIT

**Application #:** 60/401,288      **Country:** U.S. Provisional  
**Date filed:** 8/6/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** POLYMER-TETHERED NANOPARTICULATES

**Application #:** 60/401,249      **Country:** U.S. Provisional  
**Date filed:** 8/6/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** CHEMICAL VAPOR DEPOSITION AND POWDER FORMATION DEVICES, METHODS AND PRODUCTS.

**Application #:** 60/406,070      **Country:** U.S. Provisional  
**Date filed:** 8/27/2002      **Status:**

**Government Contract**      **Licensee(s):**

**Title:** CONFINED CHEMICAL REACTIONS

**Application #:** 60/406,114      **Country:** U.S. Provisional  
**Date filed:** 8/27/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**

<b>Title:</b> COMPRESSED GAS SOLUTIONS AND USES	<b>Application #:</b> 60/416,781	<b>Country:</b> U.S. Provisional
<b>Government Contract</b>	<b>Date filed:</b> 10/10/2002	<b>Status:</b> Filed
<b>Licensee(s):</b>		
<b>Title:</b> RESISTIVE MATERIAL	<b>Application #:</b>	<b>Country:</b> U.S.
<b>Government Contract</b>	<b>Date filed:</b> 10/18/2002	<b>Status:</b> Filed
<b>Licensee(s):</b>		
<b>Title:</b> TUNABLE CAPACITORS USING FLUID DIELECTRICS	<b>Application #:</b> PCT/US02/33328	<b>Country:</b> International
<b>Government Contract</b>	<b>Date filed:</b> 10/18/2002	<b>Status:</b> Filed
<b>Licensee(s):</b>		
<b>Title:</b> CARBONACEOUS MATERIALS	<b>Application #:</b> 60/425,236	<b>Country:</b> U.S. Provisional
<b>Government Contract</b>	<b>Date filed:</b> 11/12/2002	<b>Status:</b> Filed
<b>Licensee(s):</b>		
<b>Title:</b> BARRIER COATING, METHOD OF FORMATION	<b>Application #:</b> 60/429,529	<b>Country:</b> U.S. Provisional
<b>Government Contract</b>	<b>Date filed:</b> 11/27/2002	<b>Status:</b> Filed
<b>Licensee(s):</b>		
<b>Title:</b> NEUROLOGICAL METHODS AND DEVICES	<b>Application #:</b> 60/430,636	<b>Country:</b> U.S. Provisional
<b>Government Contract</b>	<b>Date filed:</b> 12/3/2002	<b>Status:</b> Filed
<b>Licensee(s):</b>		
<b>Title:</b> LIQUID ATOMIZATION METHODS AND DEVICES	<b>Application #:</b>	<b>Country:</b> Hong Kong

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Date filed:**      12/17/2002      **Status:**      Filed

**Title:**      POLYMER COATINGS

**Application #:**      10/311,785      **Country:**      U.S.

**Date filed:**      12/18/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:**      POLYMER COATINGS

**Application #:**      IN/PCT/2002,      **Country:**      India

**Date filed:**      12/24/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:**      METHOD OF DEPOSITING MATERIALS

**Application #:**      IN/PCT/2002,      **Country:**      India

**Date filed:**      12/24/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**      Ballard

**Title:**      POLYMER COATINGS

**Application #:**           **Country:**      China

**Date filed:**      12/30/2002      **Status:**      Advised Associate to File

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:**      NANOSTRUCTURE COATINGS

**Application #:**      03100112.0      **Country:**      Hong Kong

**Date filed:**      12/30/2002      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:**      INTEGRATED OPTIC CHIP BIOSENSORS

**Application #:**      60/438,956      **Country:**      U.S. Provisional

**Date filed:**      1/9/2003      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** REDUCED GRAIN BOUNDARY CRYSTALLINE THIN FILMS

**Application #:** 2003001 12-0      **Country:** Singapore  
**Date filed:** 1/10/2003      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** REDUCED GRAIN BOUNDARY CRYSTALLINE THIN FILMS

**Application #:** 10/332,866      **Country:** U.S.  
**Date filed:** 1/13/2003      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** REDUCED GRAIN BOUNDARY CRYSTALLINE THIN FILMS

**Application #:** 57/MUMNP/2003      **Country:** India  
**Date filed:** 1/14/2003      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** REDUCED GRAIN BOUNDARY CRYSTALLINE THIN FILMS

**Application #:** PI01125052      **Country:** Brazil  
**Date filed:** 1/14/2003      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** SELECTIVE AREA DEPOSITION AND DEVICES FORMED THEREFROM

**Application #:** 10/341,883      **Country:** U.S.  
**Date filed:** 1/14/2003      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL MATERIALS

**Application #:** 10/019,082      **Country:** U.S.  
**Date filed:** 1/27/2003      **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** METHOD OF DEPOSITING MATERIALS

**Application #:** 01948815.4      **Country:** Europe  
**Date filed:** 1/30/2003      **Status:** Advised Associate to File

**Government Contract**      **Licensee(s):**      Ballard

**Title:** POLYMER COATINGS

**Application #:**      01950670.8      **Country:**      Europe

**Date filed:**      1/30/2003      **Status:**      Advised Associate to File

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Title:** ELECTRONIC AND OPTICAL MATERIALS

**Application #:**      166/MUMNP/2003      **Country:**      India

**Date filed:**      2/3/2003      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL MATERIALS

**Application #:**      01963804.8      **Country:**      Europe

**Date filed:**      2/12/2003      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** REDUCED GRAIN BOUNDARY CRYSTALLINE THIN FILMS

**Application #:**      **Country:**      Europe

**Date filed:**      2/14/2003      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL DEVICES AND METHODS OF FORMING THESE DEVICES

**Application #:**      237/MUMNP/2003      **Country:**      India

**Date filed:**      2/18/2003      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL DEVICES AND METHODS OF FORMING THESE DEVICES

**Application #:**      10/362,435      **Country:**      U.S.

**Date filed:**      2/20/2003      **Status:**      Filed

**Government Contract**      **Licensee(s):**

**Title:** NARROW DIAMETER NEEDLE HAVING REDUCED INNER DIAMETER TIP

**Application #:** **Country:** U.S.

**Date filed:** 2/21/2003 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL DEVICES AND METHODS OF FORMING THESE DEVICES

**Application #:** 200300715 **Country:** Singapore

**Date filed:** 2/24/2003 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** FUEL CELL MEMBRANES AND CATALYTIC LAYERS

**Application #:** PCT/US03/06121 **Country:** International

**Date filed:** 2/28/2003 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** ELECTRONIC AND OPTICAL DEVICES AND METHODS OF FORMING THESE DEVICES

**Application #:** 01968113.9 **Country:** Europe

**Date filed:** 3/10/2003 **Status:** Advised associate to File

**Government Contract** **Licensee(s):**

**Title:** NARROW DIAMETER NEEDLE HAVING REDUCED INNER DIAMETER TIP

**Application #:** **Country:** Europe

**Date filed:** 3/22/2003 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** OPTICAL WAVEGUIDES AND INTEGRATED OPTICAL SUBSYSTEMS ON-A-CHIP

**Application #:** 10/398,641 **Country:** U.S.

**Date filed:** 4/4/2003 **Status:** Filed

**Government Contract** **Licensee(s):**

**Title:** OPTICAL WAVEGUIDES AND INTEGRATED OPTICAL SUBSYSTEMS ON-A-CHIP

**Application #:** **Country:** India

**Date filed:** 4/4/2003 **Status:** Filed

**Government Contract**      **Licensee(s):**

**Title:** OPTICAL WAVEGUIDES AND INTEGRATED OPTICAL SUBSYSTEMS ON-A-CHIP

**Government Contract**      **Licensee(s):**

**Application #:** 01977215.1      **Country:** Europe

**Date filed:** 4/6/2003      **Status:** Filed

**Title:** ELECTRONIC AND OPTICAL DEVICES AND METHODS OF FORMING THESE DEVICES

**Government Contract**      **Licensee(s):**

**Application #:**      **Country:** China

**Date filed:** 4/11/2003      **Status:** Filed

**Title:** ELECTROCATALYST-CONTAINING LAYER

**Government Contract**      **Licensee(s):** Ballard

**Application #:** 10/421,092      **Country:** U.S.

**Date filed:** 4/23/2003      **Status:** Filed

**EXHIBIT B4**  
PATENT APPLICATIONS OWNED BY GEORGIA TECH RESEARCH  
CORP. AND EXCLUSIVELY LICENSED BY MCT

PATENT  
REEL: 014901 FRAME: 0297

**Title:** METHODS AND APPARATUS FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Application #:**      JP-6-521369      **Country:**      Japan  
**Date filed:**      3/24/1994      **Status:**      Filed

**Title:** METHODS AND APPARATUS FOR THE COMBUSTION CHEMICAL VAPOR DEPOSITION OF FILMS AND COATINGS

**Government Contract**      **Licensee(s):**      Shipley, Ballard

**Application #:**      EP 94 911 694.1      **Country:**      Europe  
**Date filed:**      3/24/1994      **Status:**      Allowed

**Title:** INTEGRATED OPTIC INTERFEROMETRIC SENSOR

**Government Contract**      **Licensee(s):**

**Application #:**      2,233,305      **Country:**      Canada  
**Date filed:**      9/27/1996      **Status:**      Filed

**Title:** COMBUSTION CHEMICAL VAPOR DEPOSITION OF PHOSPHATE FILMS AND COATINGS

**Government Contract**      **Licensee(s):**      Shipley

**Application #:**      2,302,580      **Country:**      Canada  
**Date filed:**      3/23/2000      **Status:**      Filed

**Title:** INTEGRATED OPTIC INTERFEROMETRIC SENSOR

**Application #:**      01 123 875.5      **Country:**      Europe  
**Date filed:**      5/10/2001      **Status:**      Filed

**Government Contract      Licensee(s):**

**Title:** INTEGRATED OPTIC INTERFEROMETRIC SENSOR

**Government Contract**

**Application #:** JP 2002-198798      **Country:** Japan

**Date filed:** 7/8/2002      **Status:** Filed

**Licensee(s):**

**PATENT**  
**REEL: 014901 FRAME: 0299**

**Application #:** **Country:** Hong Kong

**Date filed:** 3/22/1999 **Status:** Filed

**Application #:** 2,267,492 **Country:** Canada

**Date filed:** 3/29/1999 **Status:** Filed

**Application #:** 99/DEL/553 **Country:** India

**Date filed:** 4/8/1999 **Status:** Filed

**Application #:** 129493 **Country:** Israel

**Date filed:** 4/18/1999 **Status:** Filed

**Application #:** 993700 **Country:** Mexico

**Date filed:** 4/21/1999 **Status:** Filed

**Application #:** 99303244.0 **Country:** Europe

**Government Contract**    **Licensee(s):**    MCT

**Title:** METHOD FOR FORMING THIN FILM RESISTORS

**Government Contract**    **Licensee(s):**    MCT

**Title:** METHOD FOR FORMING THIN FILM RESISTORS

**Government Contract**    **Licensee(s):**    MCT

**Title:** METHOD FOR FORMING THIN FILM RESISTORS

**Government Contract**    **Licensee(s):**    MCT

**Title:** CONTINUOUS FEED COATER

**Government Contract**    **Licensee(s):**    MCT

**Title:** CONTINUOUS FEED COATER

**Government Contract**    **Licensee(s):**    MCT

**Title:** CONTINUOUS FEED COATER

**Government Contract**    **Licensee(s):**    MCT

**Application #:**    99013576                      **Country:**    Brazil

**Date filed:**        4/28/1999    **Status:**        Filed

**Application #:**    991063589                      **Country:**    China

**Date filed:**        4/29/1999    **Status:**        Filed

**Application #:**    11124575                      **Country:**    Japan

**Date filed:**        4/30/1999    **Status:**        Filed

**Application #:**    01307874.6-2307                      **Country:**    Europe

**Date filed:**        9/14/2001    **Status:**        Filed

**Application #:**    2,357,324                      **Country:**    Canada

**Date filed:**        9/14/2001    **Status:**        Filed

**Application #:**    90122820                      **Country:**    Taiwan

**Date filed:**        9/14/2001    **Status:**        Filed

**Title:** CONTINUOUS FEED COATER

**Application #:** 10-2001-0057028 **Country:** South Korea

**Date filed:** 9/15/2001 **Status:** Filed

**Government Contract** **Licensee(s):** MCT

**Title:** CONTINUOUS FEED COATER

**Application #:** 09/952,881 **Country:** U.S.

**Date filed:** 9/15/2001 **Status:** Filed

**Government Contract** **Licensee(s):** MCT

**Title:** CONTINUOUS FEED COATER

**Application #:** 282258/2001 **Country:** Japan

**Date filed:** 9/17/2001 **Status:** Filed

**Government Contract** **Licensee(s):** MCT

**Title:** RESISTIVE MATERIALS

**Application #:** **Country:** Europe

**Date filed:** 7/3/2002 **Status:** Filed

**Government Contract** **Licensee(s):** MCT

**Title:** RESISTIVE MATERIALS

**Application #:** **Country:** China

**Date filed:** 7/3/2002 **Status:** Filed

**Government Contract** **Licensee(s):** MCT

**Title:** RESISTIVE MATERIALS

**Application #:** **Country:** Taiwan

**Date filed:** 7/3/2002 **Status:** Filed

**Government Contract** **Licensee(s):** MCT

**Title:** RESISTIVE MATERIALS

**Application #:** **Country:** South Korea

**Date filed:** 7/3/2002 **Status:** Filed

**Government Contract**      **Licensee(s):**      MCT

**Title:** RESISTIVE MATERIALS

**Application #:**      **Country:** Japan

**Date filed:** 7/3/2002      **Status:** Filed

**Government Contract**      **Licensee(s):**      MCT

**Title:** RESISTIVE MATERIALS

**Application #:** 10/190,292      **Country:** U.S.

**Date filed:** 7/3/2002      **Status:** Filed

**Government Contract**      **Licensee(s):** MCT

**EXHIBIT B6**  
**PATENTS OWNED BY SHIPLEY AND LICENSED EXCLUSIVELY  
BY MCT OUTSIDE THE FIELD OF EMBEDDED PASSIVES**

**Title:** THE DEPOSITION OF RESISTOR MATERIALS DIRECTLY ON INSULATING SUBSTRATES

<b>Patent #:</b>	6,210,592	<b>Country:</b>	U.S.
<b>Issue date:</b>	4/3/2001	<b>Status:</b>	Issued, Expires 4/29/2018
<b>Government Contract</b>	<b>Licensee(s):</b>	MCT	

**Title:** FORMATION OF THIN FILM RESISTORS

<b>Patent #:</b>	6,329,899	<b>Country:</b>	U.S.
<b>Issue date:</b>	12/11/2001	<b>Status:</b>	Issued, Expires 4/29/18
<b>Government Contract</b>	<b>Licensee(s):</b>	MCT	

**Title:** METHOD FOR FORMING THIN FILM RESISTORS

<b>Patent #:</b>	0322287	<b>Country:</b>	South Korea
<b>Issue date:</b>	1/15/2002	<b>Status:</b>	Issued, Expires 4/29/98
<b>Government Contract</b>	<b>Licensee(s):</b>	MCT	

**Title:** METHOD FOR FORMING THIN FILM RESISTORS

<b>Patent #:</b>	SG68713	<b>Country:</b>	Singapore
<b>Issue date:</b>	2/26/2002	<b>Status:</b>	Issued, Expires 4/29/18
<b>Government Contract</b>	<b>Licensee(s):</b>	MCT	

**Title:** METHOD FOR FORMING THIN FILM RESISTORS

<b>Patent #:</b>	159129	<b>Country:</b>	Taiwan
<b>Issue date:</b>	11/5/2002	<b>Status:</b>	Allowed
<b>Government Contract</b>	<b>Licensee(s):</b>	MCT	

**Title:** FORMATION OF THIN FILM RESISTORS

<b>Patent #:</b>	6,500,350	<b>Country:</b>	U.S.
<b>Issue date:</b>	12/31/2002	<b>Status:</b>	Issued

**Government Contract      Licensee(s):      MCT**

**EXHIBIT C**  
**Trademarks**

<b>MARK</b>	<b>TYPE OF MARK</b>	<b>FILING DATE (if filed)</b>	<b>SERIAL NUMBER</b>	<b>DATE OF FIRST USE (if used)</b>	<b>REGISTRATION NUMBER (if registered)</b>	<b>REGISTRATION DATE (if registered)</b>
NANOMISER	Trade/Service	9/10/1999	75/795702	10/15/2001	2579411	6/11/2002
BUILDING THE FUTURE LAYER BY LAYER	Service			7/20/1994		
MICROCOATING TECHNOLOGIES	Service			10/13/1995		
MAGICAP	Trade	11/14/2001	76/335536			
NANOMISER (Europe)		12/19/2001	00258760			

EXHIBIT D

Mask Works

None